

OVERALL PROBING ACCURACY AT ELEVATED TEMPERATURE

Phil Seitzer Lucent Technologies - Allentown
Rick Langford Lucent Technologies - Orlando



OUTLINE

- Introduction
- Analysis of probe mark placement error
- Case Study - A 12" interface at elevated temperature
 - History of Problem
 - Work in progress - solutions tried & lessons learned
 - Further work
- General Observations



CHALLENGES TO WAFER PROBE

- Dimensions (including bond pads) keep growing smaller.
- The assembly folks (especially wire bonder suppliers) have forged ahead in capability.
 - Wafer probe is now the primary barrier that designers must conquer when they want smaller bond pads.
- More and more devices require elevated temperature wafer probe.

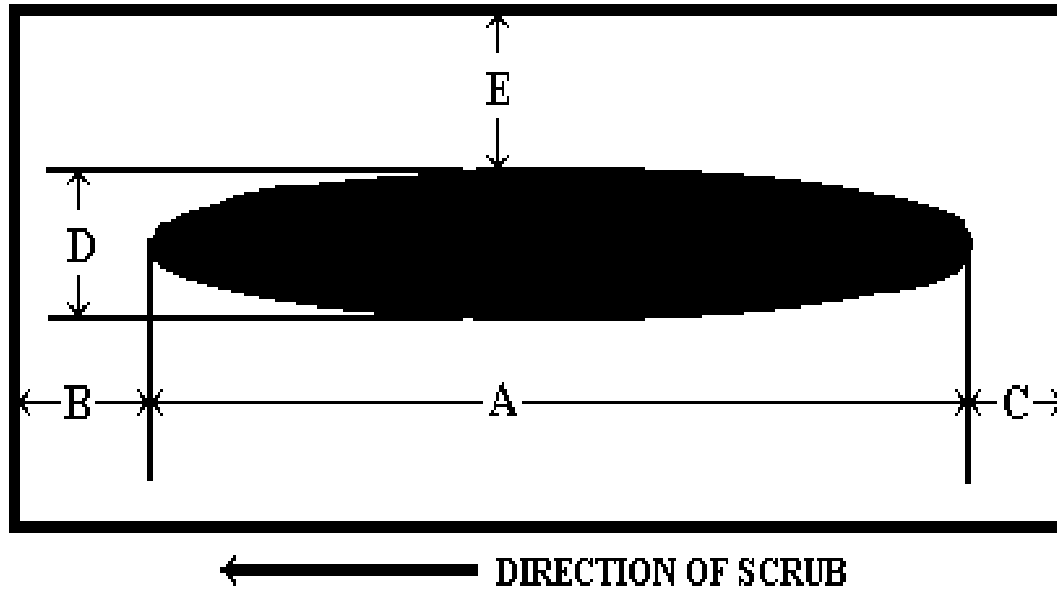


Analysis of Probe Mark Placement Error (Dimensional Allocation)

- Dimensional Allocation is a method developed at Lucent Technologies to compare the performance of various prober and interface combinations.
- Utilizes actual measurements wherever possible.
- Attempts to include the error effects of temperature changes.



Bond Pad Dimensional Analysis



A. Maximum Scrub Length **59.6 μm**
B. Leading Damage Margin **5 μm**
C. Heel Margin **5 μm**
D. Maximum Scrub Width **27 μm**
E. Width Margin **15 μm**

F. Maximum Prober Alignment Error **5 μm**
G. Probe Positional Error **6.5 μm**
H. Interface Stability Error **3.0 μm**



Bond Pad Dimensional Analysis

- Prober Alignment Error - manufacturer's spec 5 μm
- Probe Positional Error - condition of probe card
 - Carefully maintained cards 6-7 μm (3 \leftarrow)
 - Normal production cards 12-14 μm
- Interface Stability Error
 - Difficult to measure - uses upward-looking prober camera
 - Includes changes in position due to temperature

	Error (μm)
Tester A	6.8
Tester B	15.6
Tester B-2	1.3
Tester C	7.7
Tester D	5.5



Bond Pad Dimensional Analysis

- Combined placement error (1σ)
= $((F/3)^2 + (G/3)^2 + (H/3)^2)^{1/2}$
- For Tester B:
= $((5/3)^2 + (6.5/3)^2 + (15.6/3)^2)^{1/2} \mu\text{m}$
= $5.85 \mu\text{m}$
- Resulting 3σ placement error:
= $17.55 \mu\text{m}$



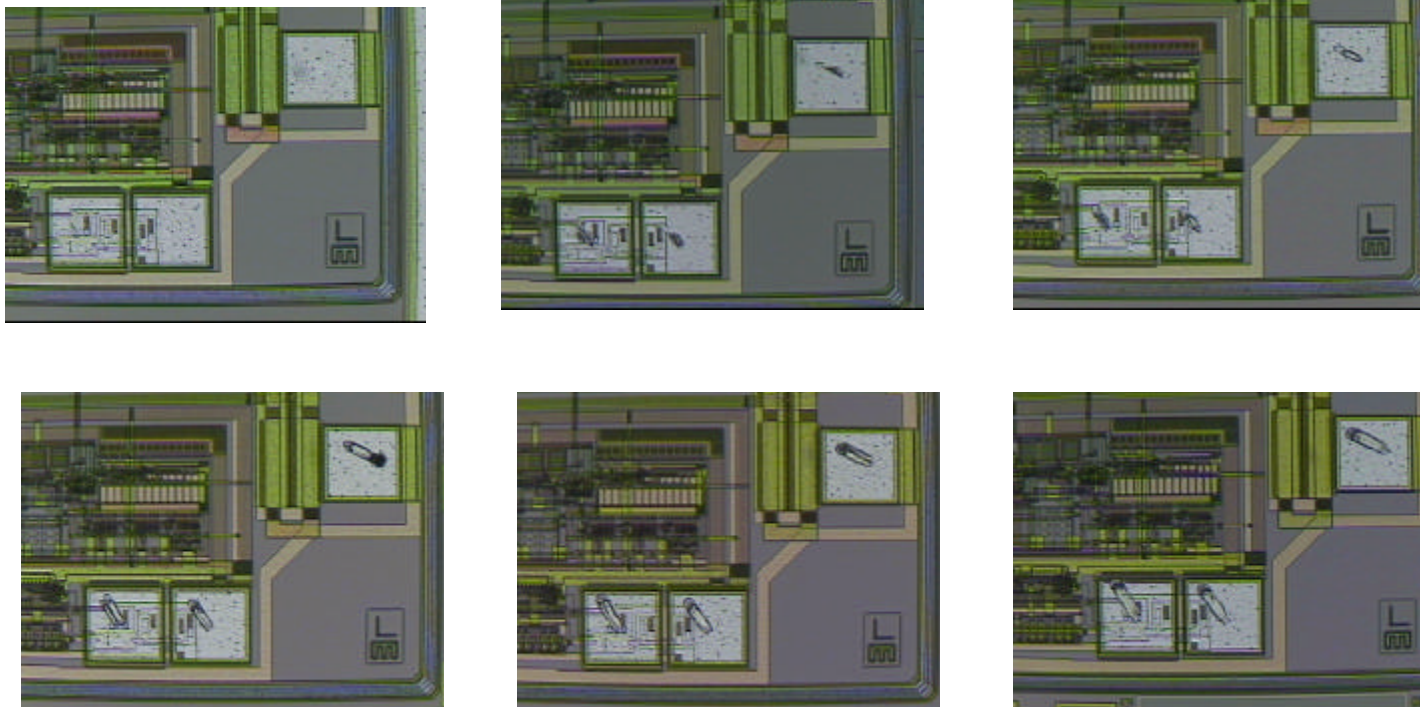
CASE STUDY - A 12" Probe Card - WAFER PROBER INTERFACE

- Issues apply to many large test heads.
- Issues are not new - most if not all have been discussed here before.
- Much support has been provided by test system, probe card, and prober vendors.



PROBLEM: Testing at 100° C

First site



Last site



Performance of Standard 12” Probe Card Interface

	Chuck Temp.	X	Y	Z	ΔX	ΔY	ΔZ
Initial reading	25.0°C	560.1 μ M	87.5 μ M	20348 μ M	-----	-----	-----
After Re-Docking	25.0°C	571.5 μ M	86.7 μ M	20289 μ M	11.4 μ M	0.8 μ M	59 μ M
10 minute soak	100°C	560.2 μ M	72.3 μ M	20248 μ M	0.1 μ M	15.2 μ M	100 μ M

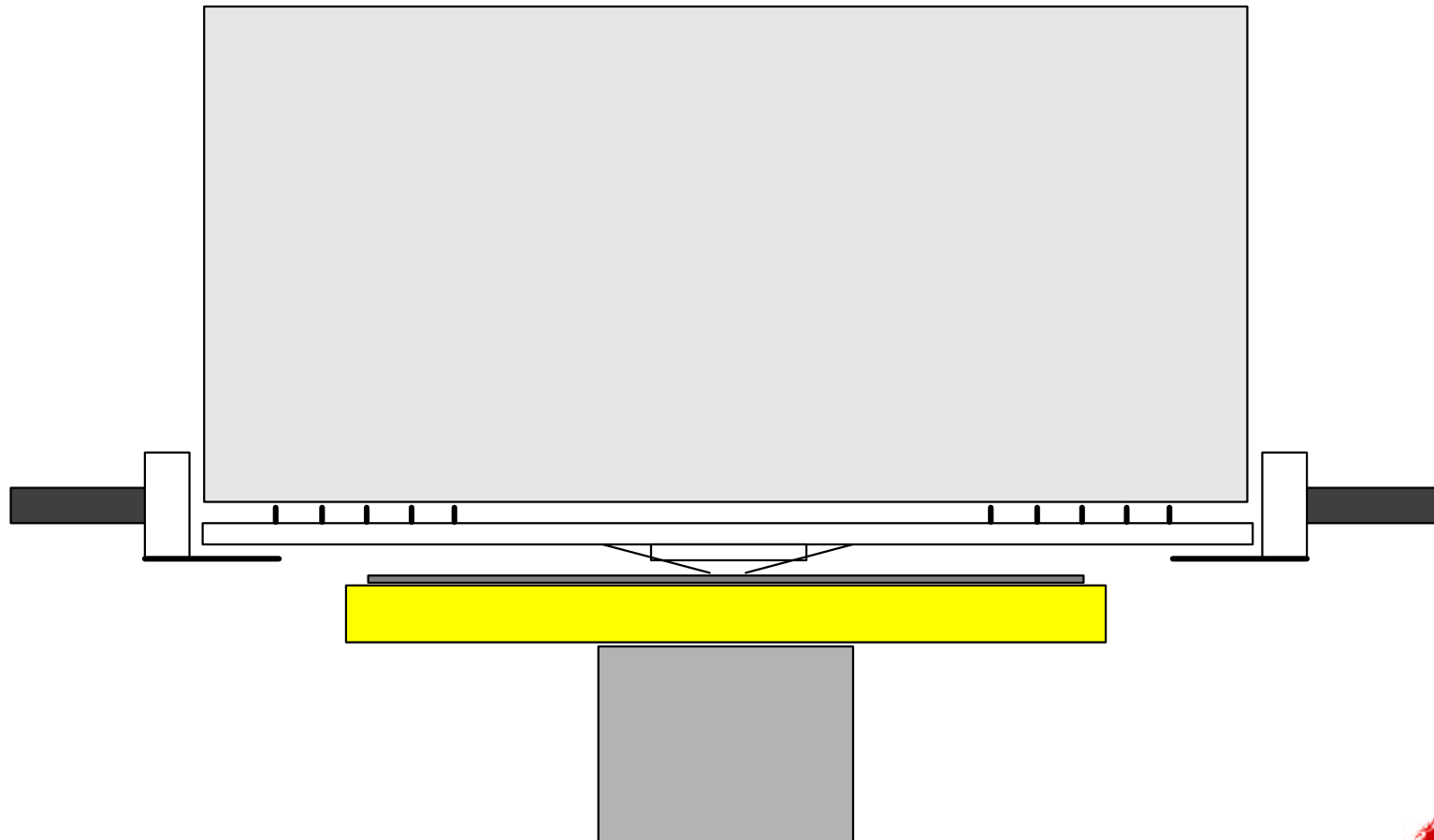


Some Factors Possibly Affecting Accuracy

- High and/or Uneven Pogo-pin Pressure
- Inadequate Probe Card Support
- Inadequate Probe Card Stiffness
- Uneven probe card heating due to chuck position
- Temperature gradient between top & bottom of card
- Not enough clearance between card edge and holder
- Possible interference with alignment pins as card expands
- Inadequate soak time
- Possible epoxy softening



INTERFACE DIAGRAM

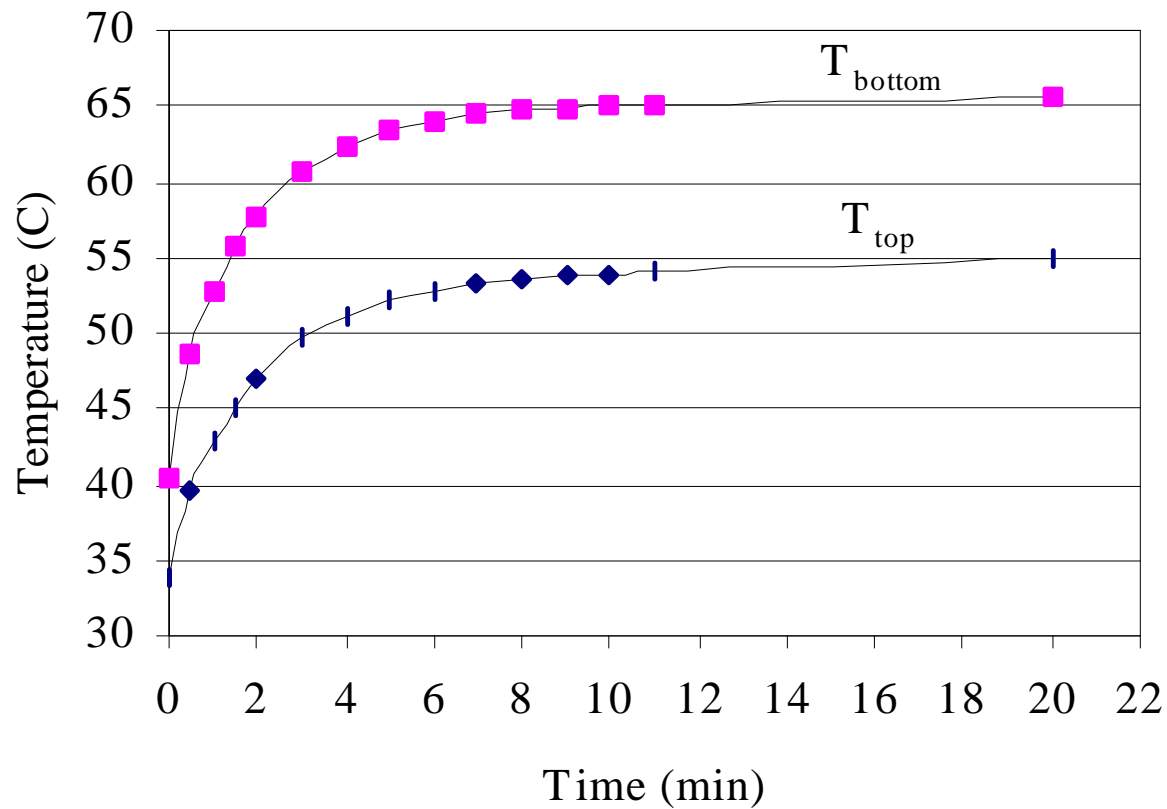


Corrective Strategies

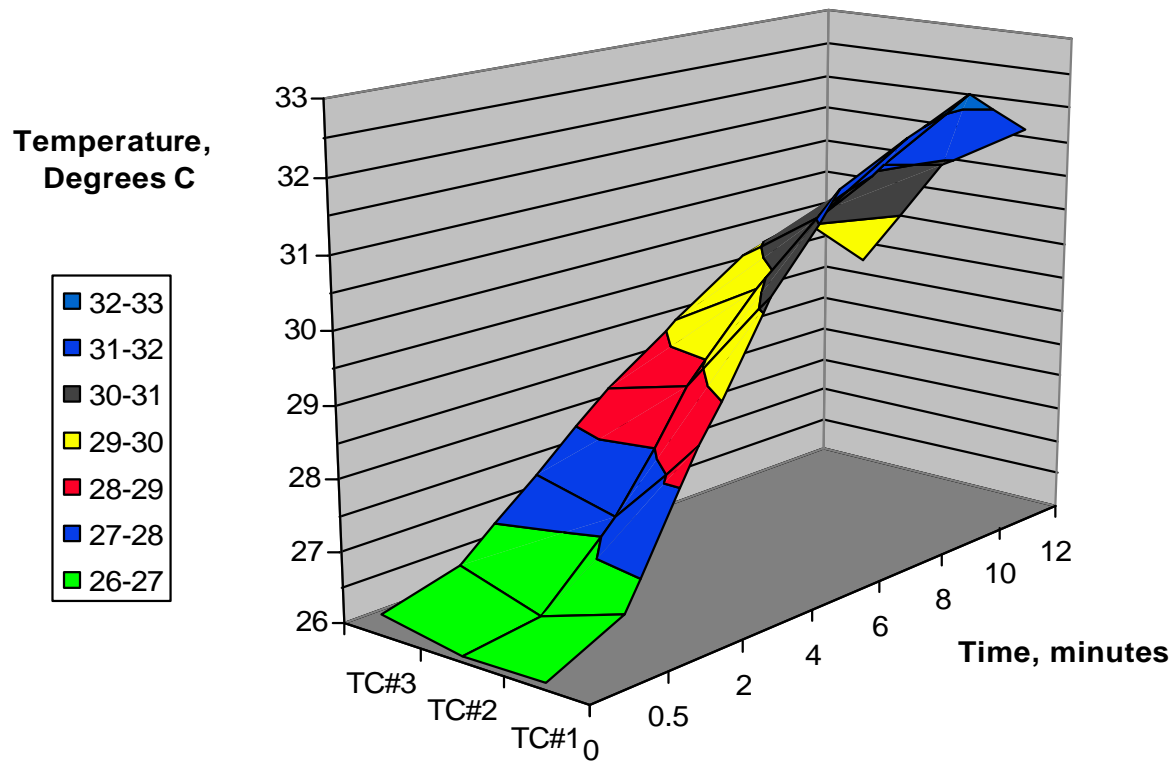
- Thermal
 - Minimize the temperature seen by the probe card.
 - Minimize the temperature gradient.
 - Allow sufficient soak time.
- Mechanical
 - Revise the mechanical design of the probe card.
 - Improve the probe card holder.



Vertical Temperature Gradient



Radial Temperature Gradient



PROBE CARD HEATING

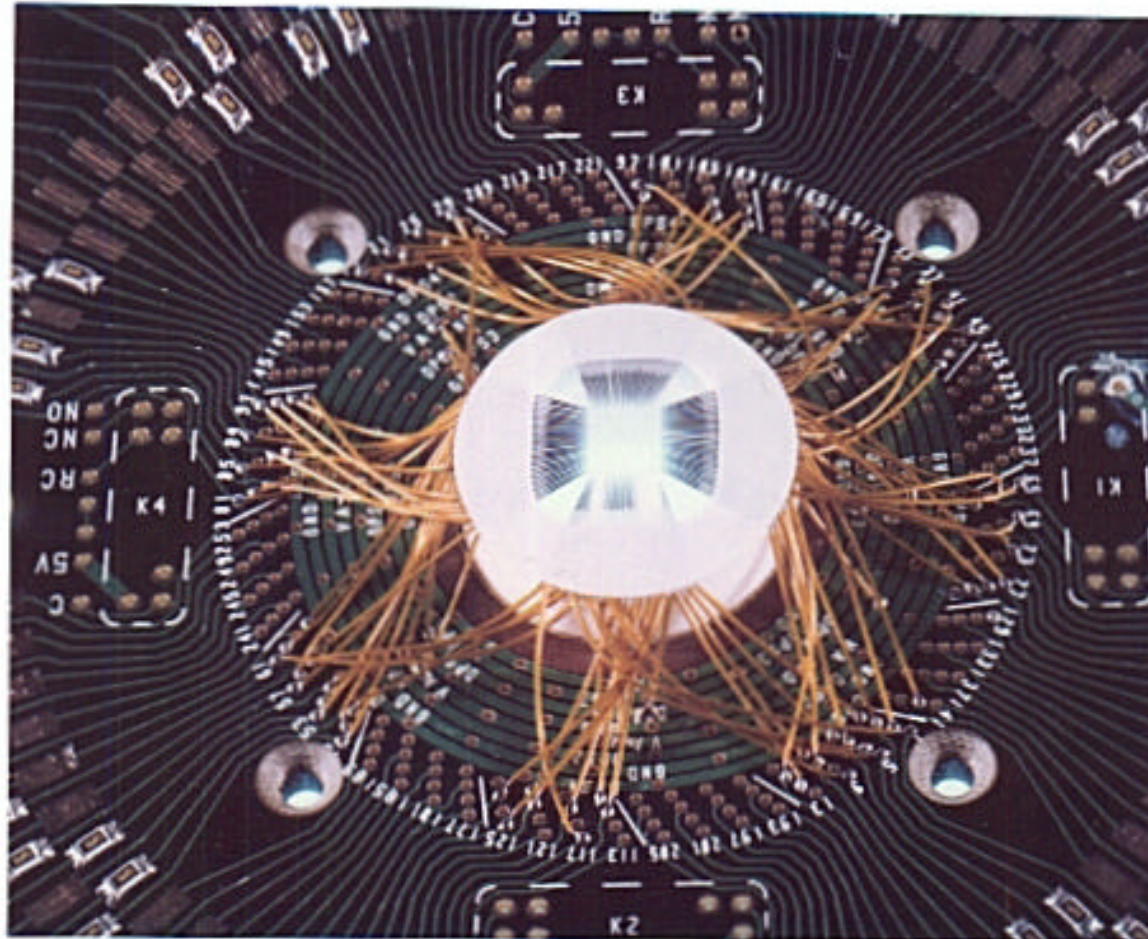
- Soak Time
 - Long soak time required for stabilization and top to bottom gradient will still exist.
 - Uneven heating from moving chuck still causes probe card x-y movement.
 - Will not solve problem.
- Heat Shield
 - Tends to increase Temperature gradient in x-y Plane.
- Probe Depth

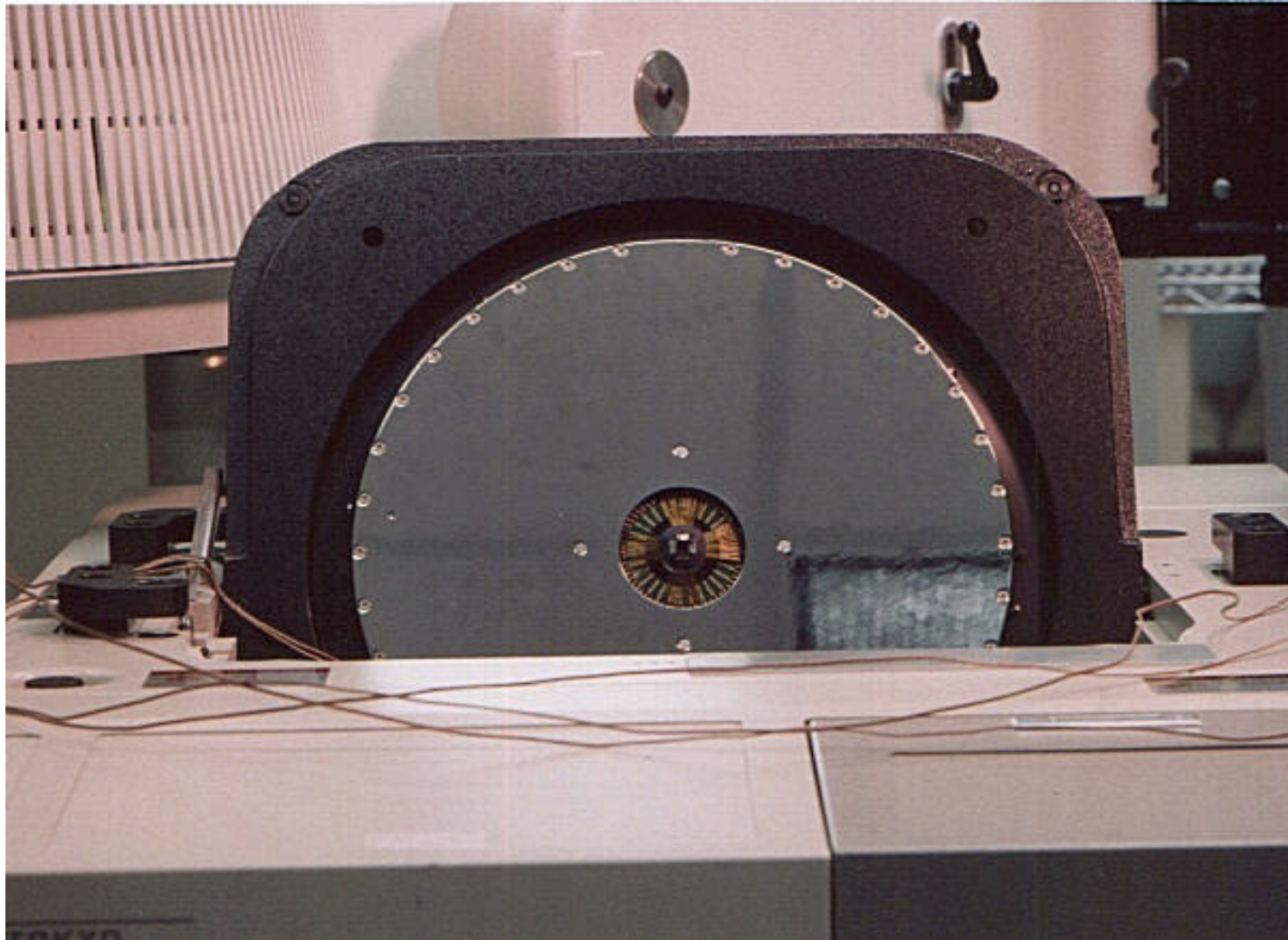


Mechanical Effects

- Probe Card Stiffness
 - New Materials
- Interface Stiffness
 - Probe card tray as bottom side stiffener
 - Top side stiffener
- Interface Stability
 - Probe card secured to tray







EVALUATION

- Work is currently in progress.
- The impact of any single change, made separately, has not been dramatic.
- All improvements made together are expected to produce a solution capable of being used in production.



General Observations

- The prober - probe card - tester interface for many large systems is complex - mechanically, electrically and thermally.
- Industry trends are placing more and more demands on this design, requiring attention to mechanical and thermal characteristics.
- Interface stability, although difficult to measure, is an important parameter when high accuracy probing is required.



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